



National Aeronautics and Space
Administration
Jet Propulsion Laboratory
California Institute of Technology

Electric **F**ield **C**onjugation-based wavefront correction algorithm for high contrast imaging systems

Experimental results

Amir Give'on¹

Brian Kern¹

Stuart Shaklan¹

Dwight Moody¹

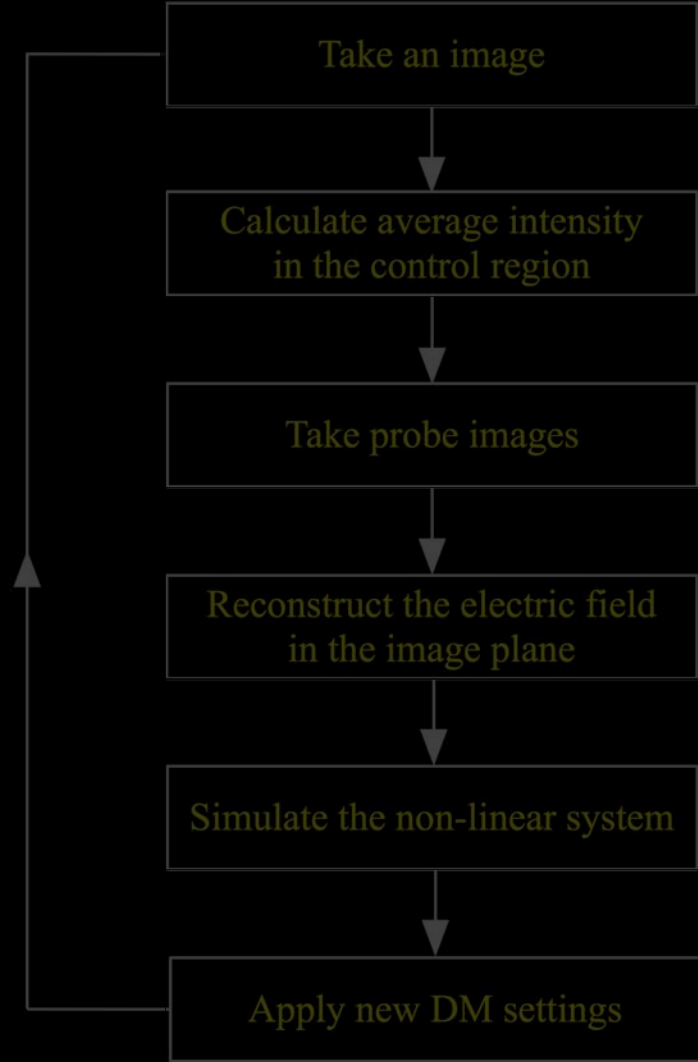
Rus Belikov²

¹ Jet Propulsion Laboratory

² Princeton University

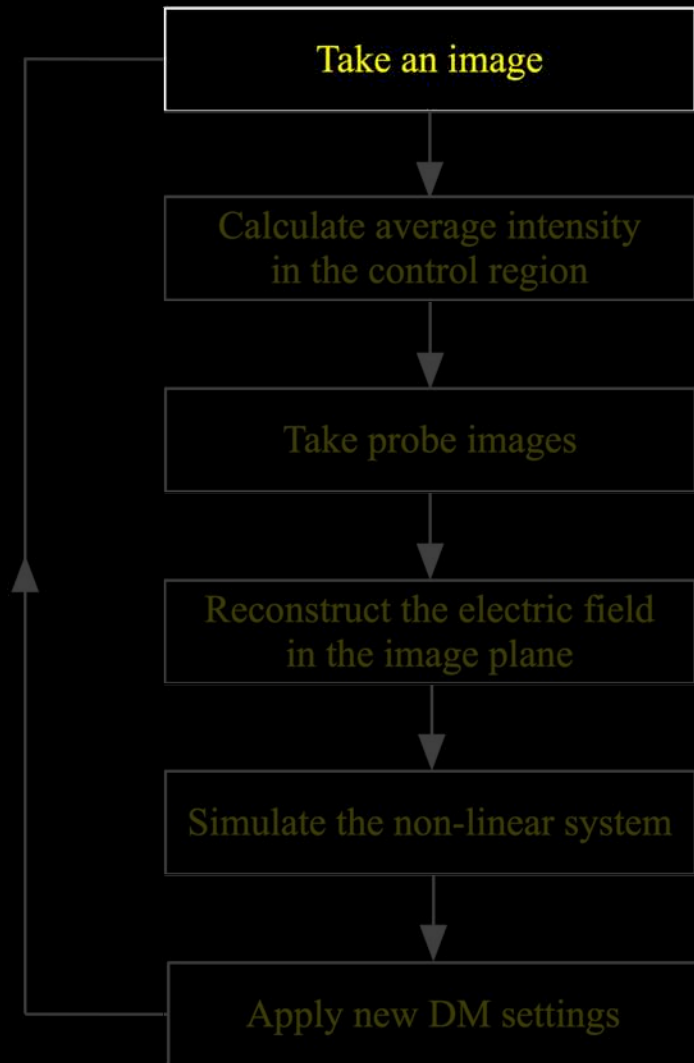


The algorithm

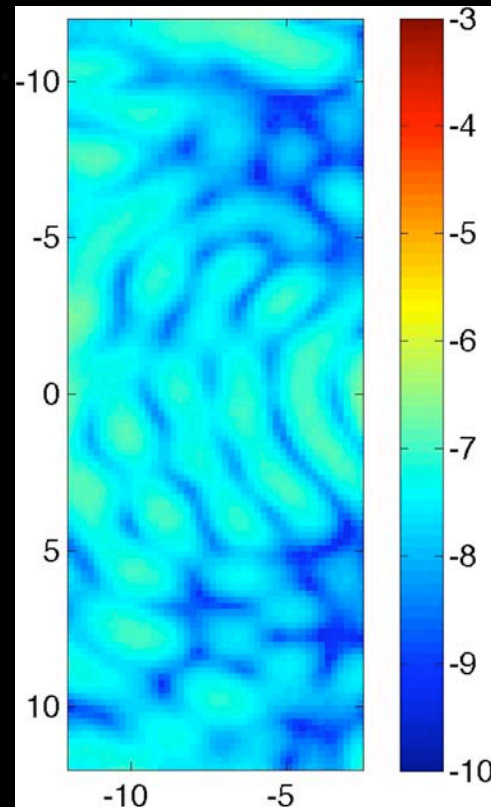




The algorithm



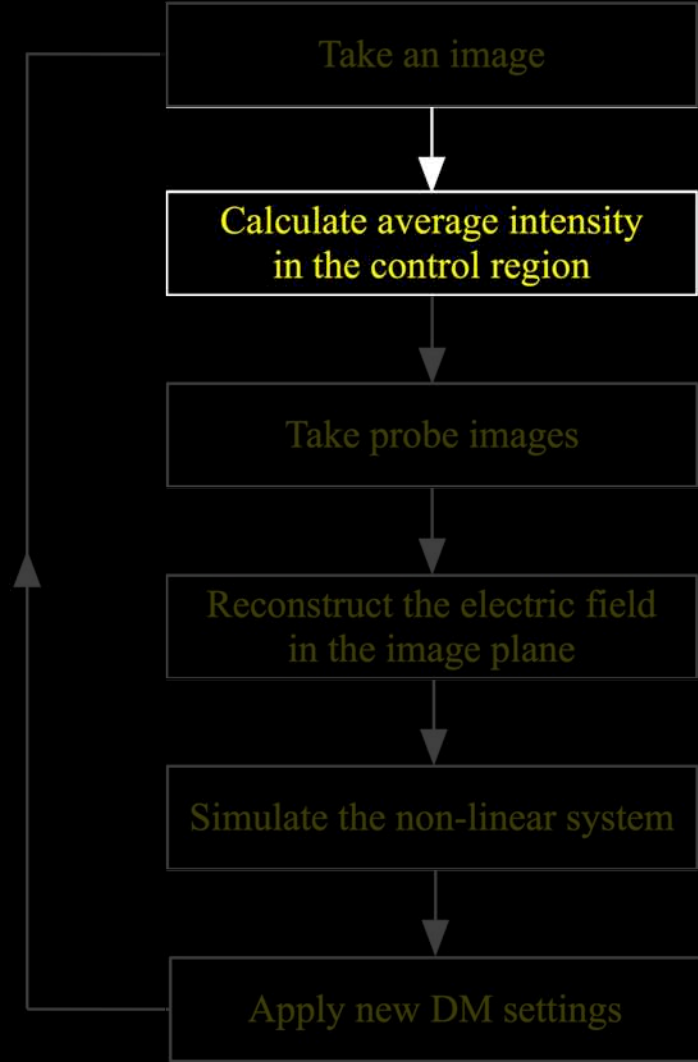
Measured image



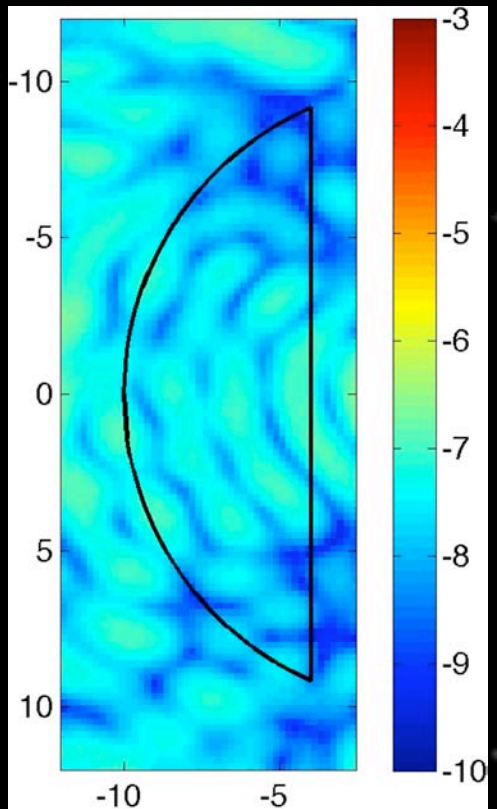
Measurements were taken at 2% around 800nm



The algorithm



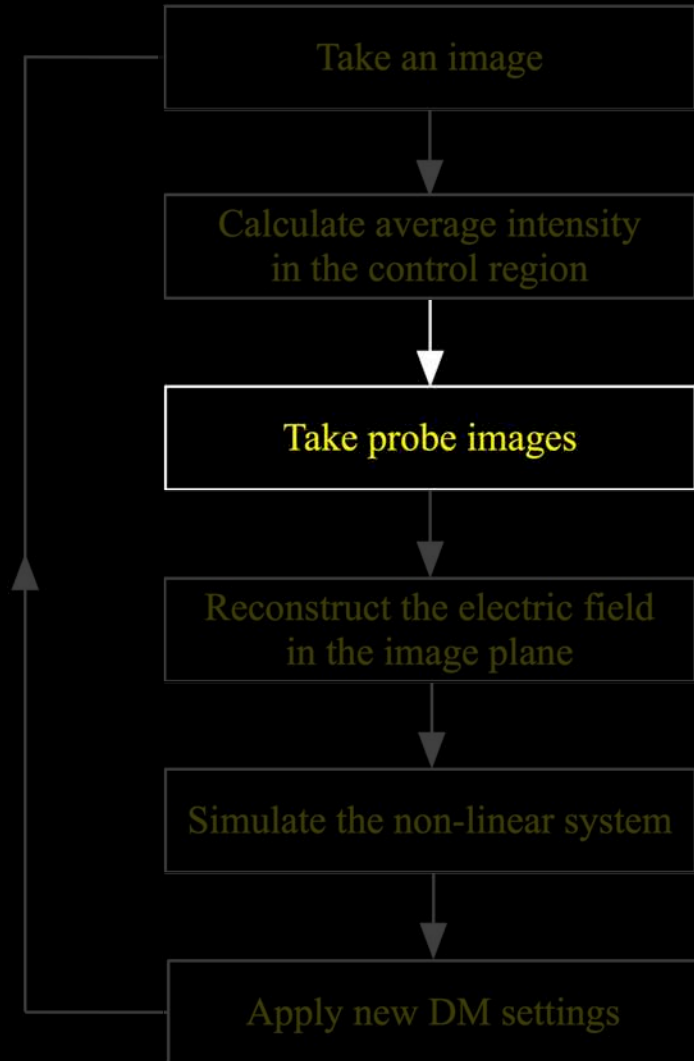
Measured image



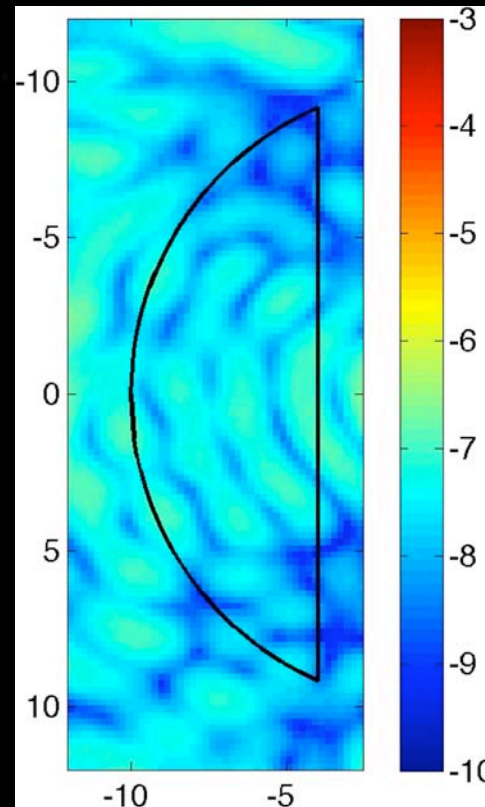
Measurements were taken at 2% around 800nm



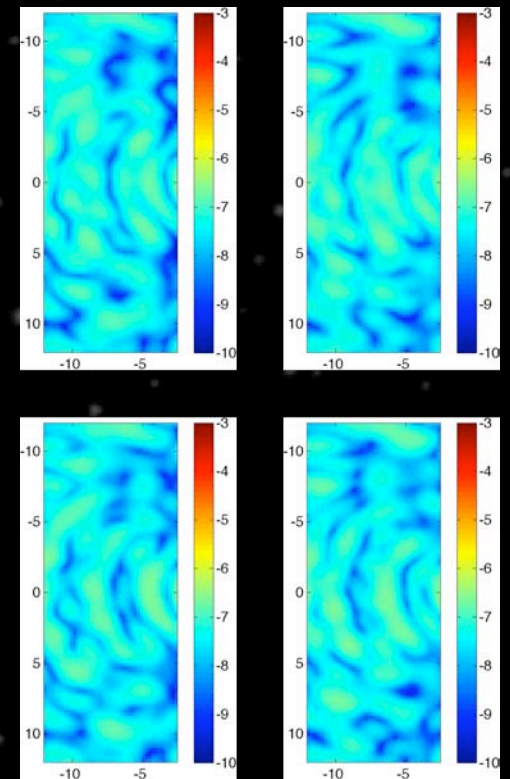
The algorithm



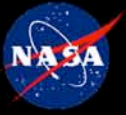
Measured
image



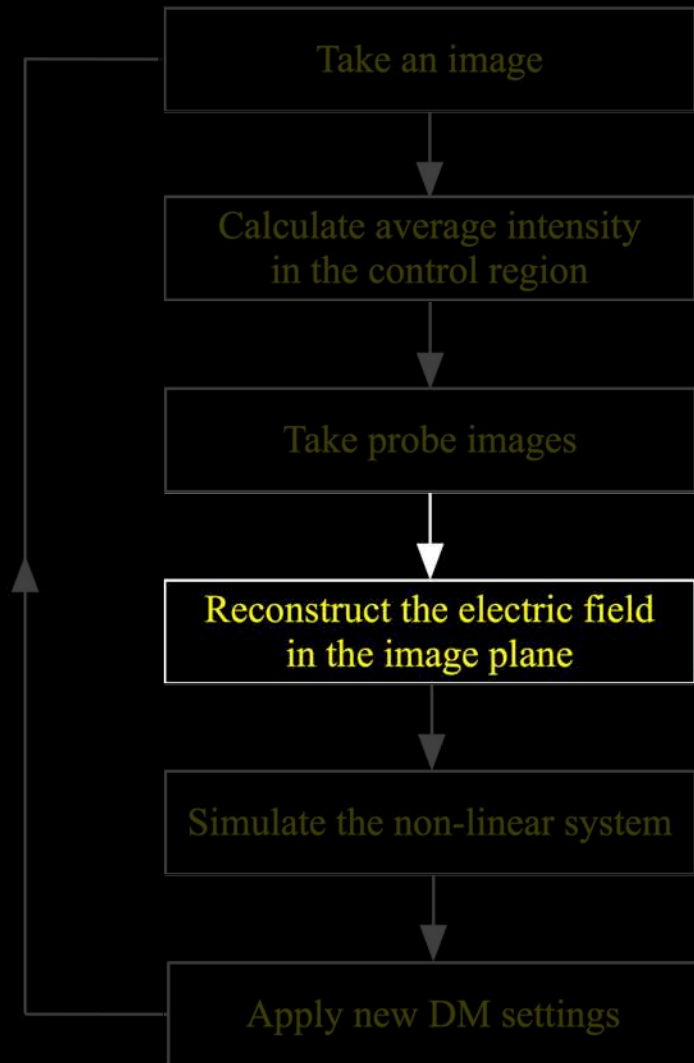
Probe images



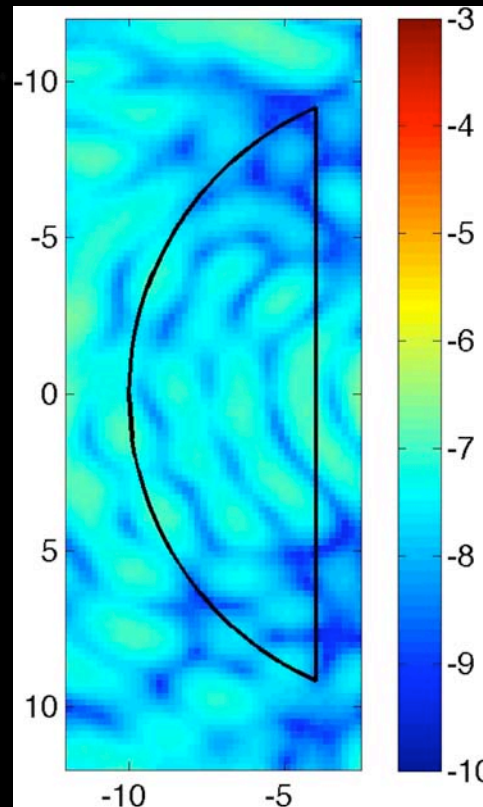
Measurements were taken at 2% around 800nm



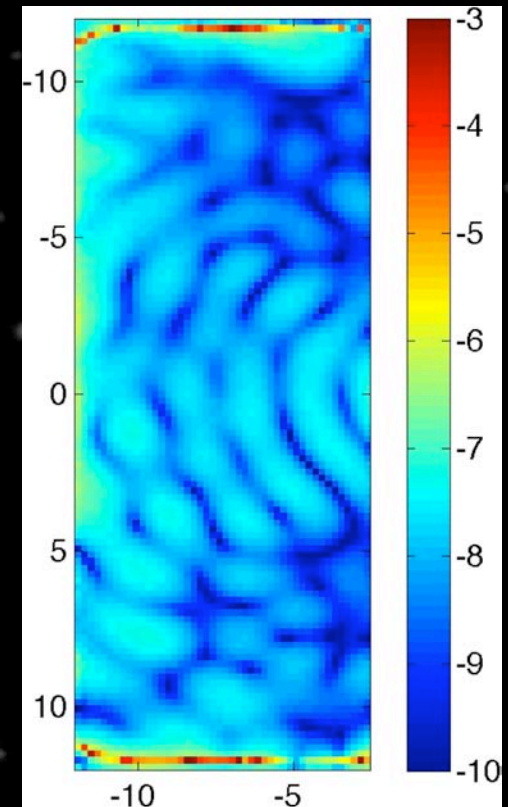
The algorithm



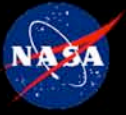
Measured image



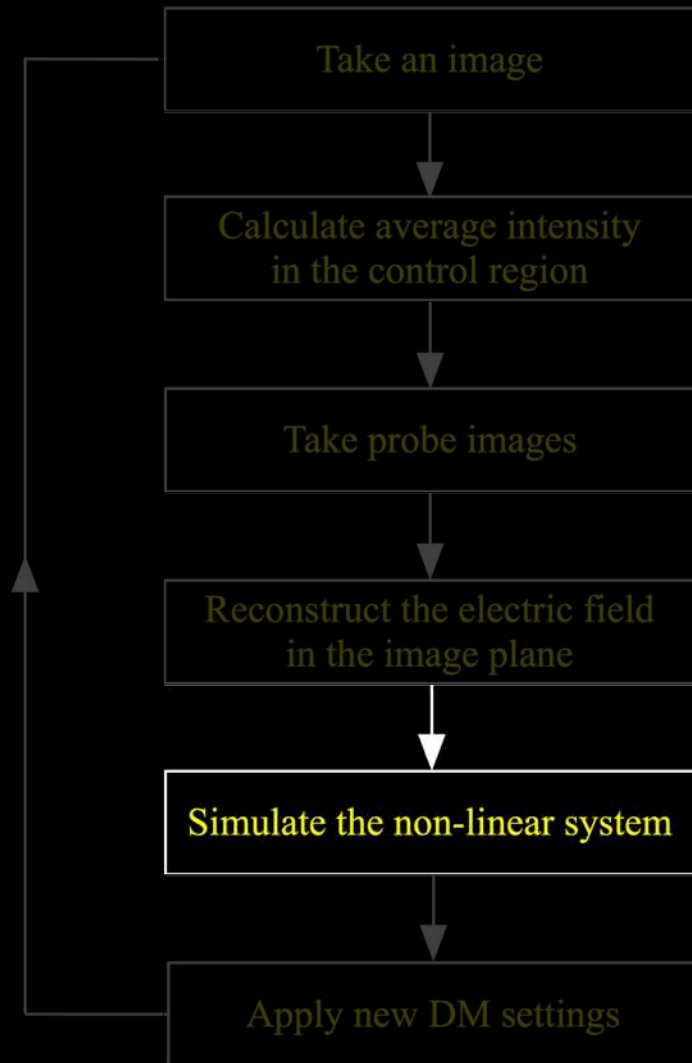
Intensity from reconstructed electric field



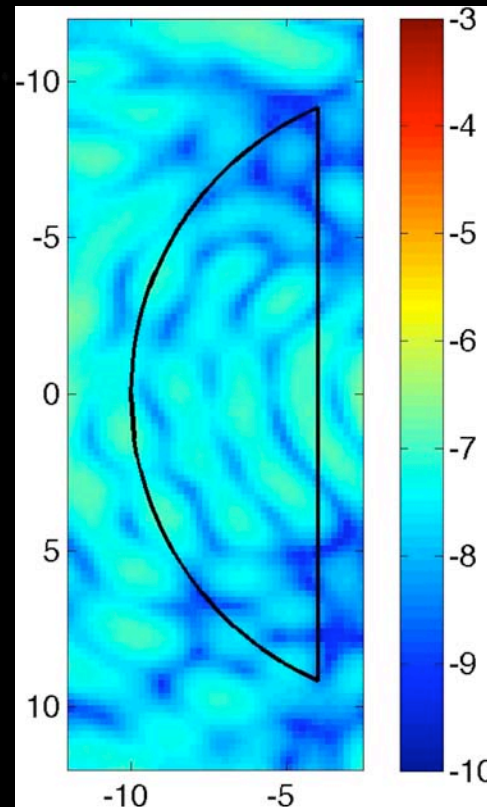
Measurements were taken at 2% around 800nm



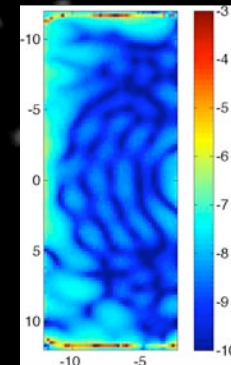
The algorithm



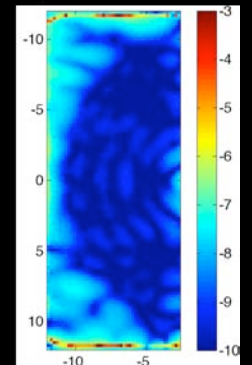
Measured image



After one iteration



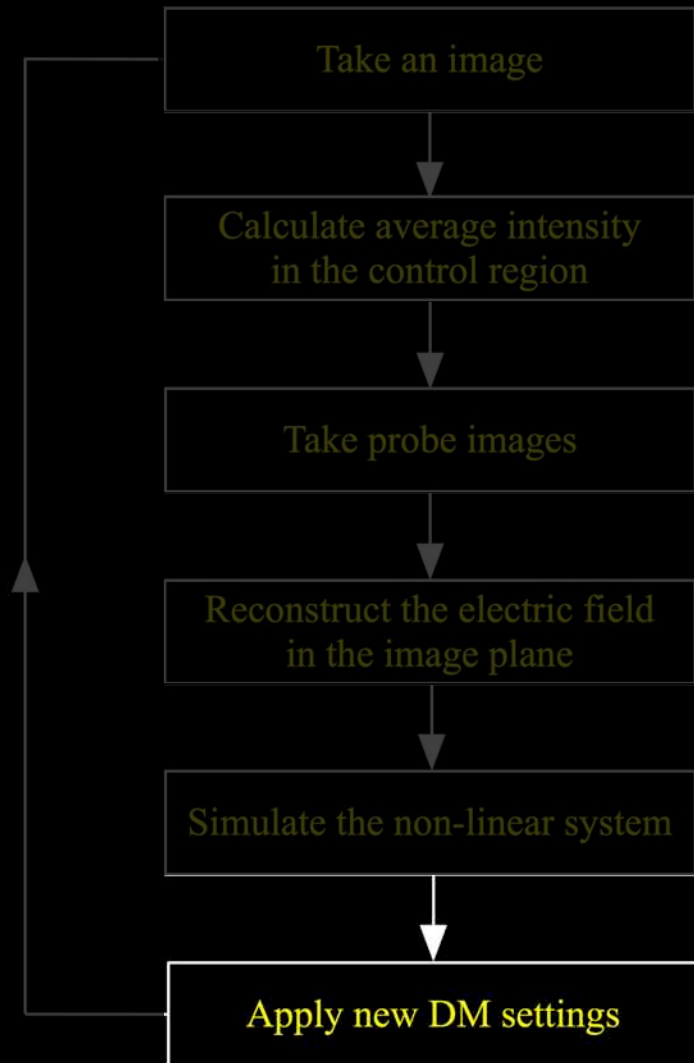
After five iterations



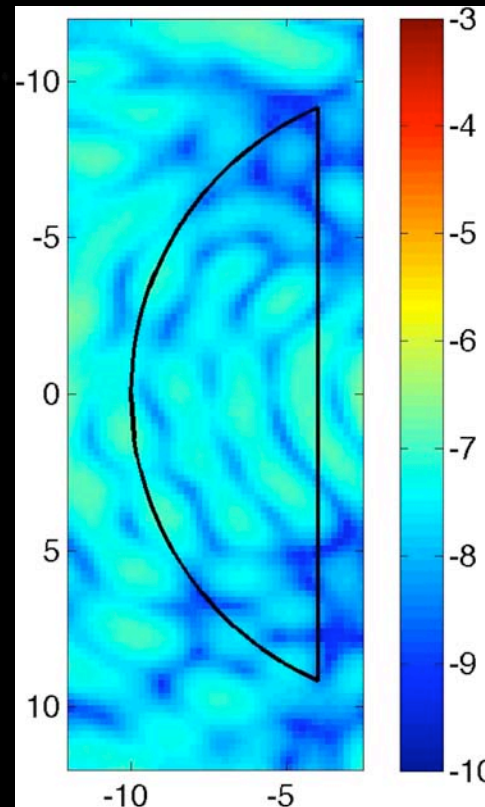
Measurements were taken at 2% around 800nm



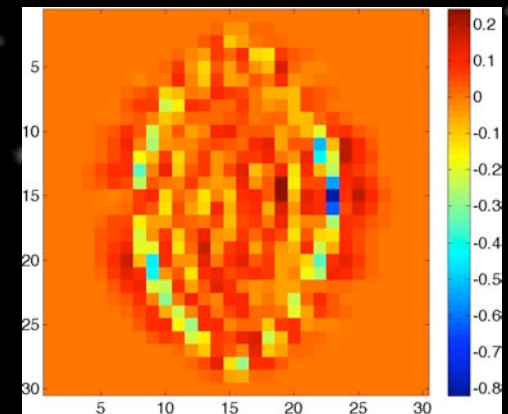
The algorithm



Measured image



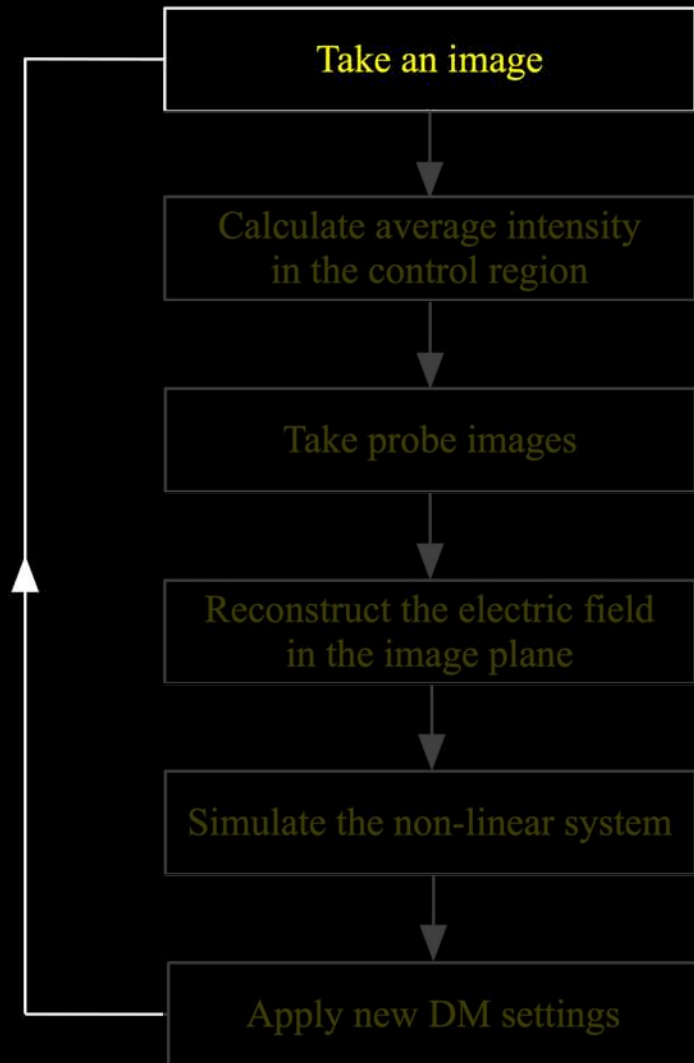
Change in DM actuators



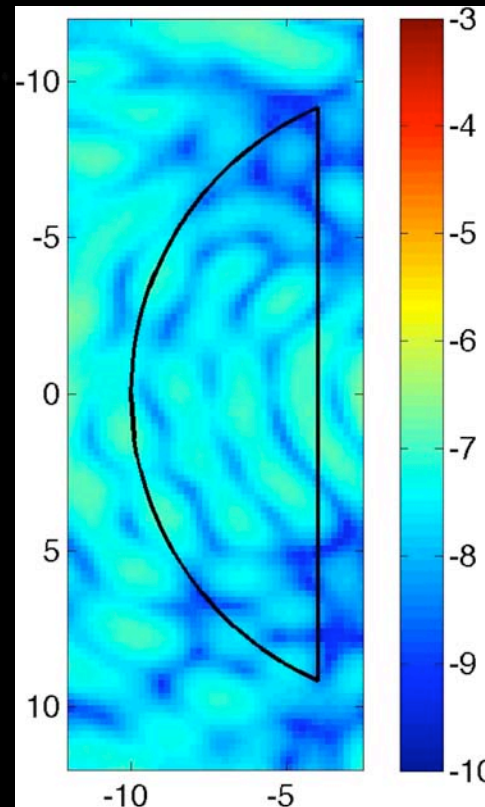
Measurements were taken at 2% around 800nm



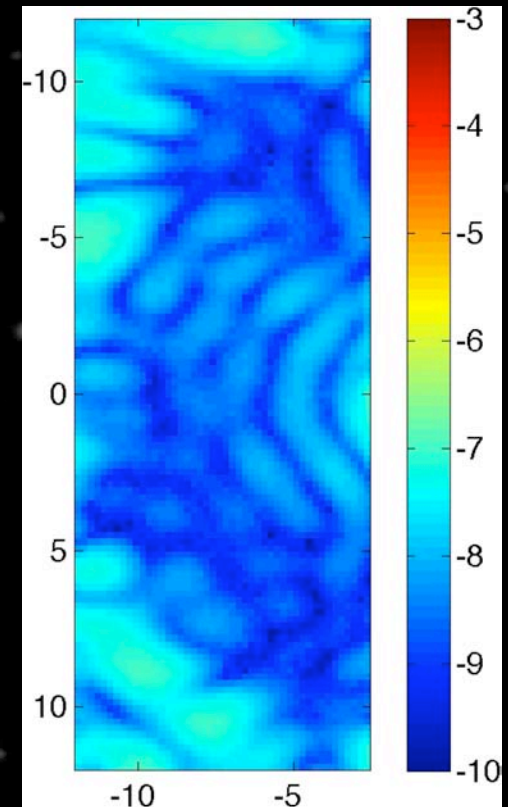
The algorithm



Measured image



New measured image



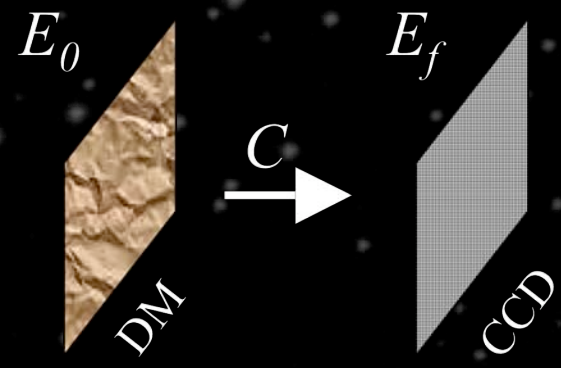
Measurements were taken at 2% around 800nm



The reconstruction stage

Let C be the transformation between the electric field in DM plane to the electric field in the image plane

$$E_f = C \{E_0\}$$





The reconstruction stage

Let C be the transformation between the electric field in DM plane to the electric field in the image plane

$$E_f = C \{E_0\}$$

For a corrected system with phase and amplitude aberrations, the electric field in the DM plane can be modeled as

$$E_0 = A e^{\alpha + i\beta} e^{i\psi}$$



The reconstruction stage

Let C be the transformation between the electric field in DM plane to the electric field in the image plane

$$E_f = C \{E_0\}$$

For a corrected system with phase and amplitude aberrations, the electric field in the DM plane can be modeled as

$$E_0 = Ae^{\alpha+i\beta} e^{i\psi}$$

The electric field in the image plane can be approximated as

$$E_f \approx C \{Ae^{\alpha+i\beta}\} + iC \{A\psi\}$$



The reconstruction stage

Let C be the transformation between the electric field in DM plane to the electric field in the image plane

$$E_f = C \{E_0\}$$

For a corrected system with phase and amplitude aberrations, the electric field in the DM plane can be modeled as

$$E_0 = Ae^{\alpha+i\beta} e^{i\psi}$$

The electric field in the image plane can be approximated as

$$E_f \approx C \{Ae^{\alpha+i\beta}\} + iC \{A\psi\}$$

Then, the intensity in the image plane is given by

$$I_k \approx |C \{Ae^{\alpha+i\beta}\} + iC \{A\psi_k\}|^2$$



The reconstruction stage

Suppose we deform the DM in pairs of conjugate shapes, then, the pair of probe intensity measurements is given by

$$\begin{aligned} I_k^+ &\approx \left| C \{ A e^{\alpha + i\beta} \} + i C \{ A \psi_k \} \right|^2 \\ I_k^- &\approx \left| C \{ A e^{\alpha + i\beta} \} - i C \{ A \psi_k \} \right|^2 \end{aligned}$$



The reconstruction stage

Suppose we deform the DM in pairs of conjugate shapes, then, the pair of probe intensity measurements is given by

$$\begin{aligned} I_k^+ &\approx \left| C \{ A e^{\alpha+i\beta} \} + i C \{ A \psi_k \} \right|^2 \\ I_k^- &\approx \left| C \{ A e^{\alpha+i\beta} \} - i C \{ A \psi_k \} \right|^2 \end{aligned}$$

For each pair, at any given point in the image plane,

$$I_k^+ - I_k^- = 2C^* \{ A e^{\alpha+i\beta} \} C \{ A \psi_k \} + 2C \{ A e^{\alpha+i\beta} \} C^* \{ A \psi_k \}$$



The reconstruction stage

Suppose we deform the DM in pairs of conjugate shapes, then, the pair of probe intensity measurements is given by

$$I_k^+ \approx \left| C \{ A e^{\alpha+i\beta} \} + i C \{ A \psi_k \} \right|^2$$

$$I_k^- \approx \left| C \{ A e^{\alpha+i\beta} \} - i C \{ A \psi_k \} \right|^2$$

For each pair, at any given point in the image plane,

$$I_k^+ - I_k^- = 2C^* \{ A e^{\alpha+i\beta} \} C \{ A \psi_k \} + 2C \{ A e^{\alpha+i\beta} \} C^* \{ A \psi_k \}$$

Using all measurements, we can estimate the real and imaginary parts of the electric field in the image plane (at any given point) using:

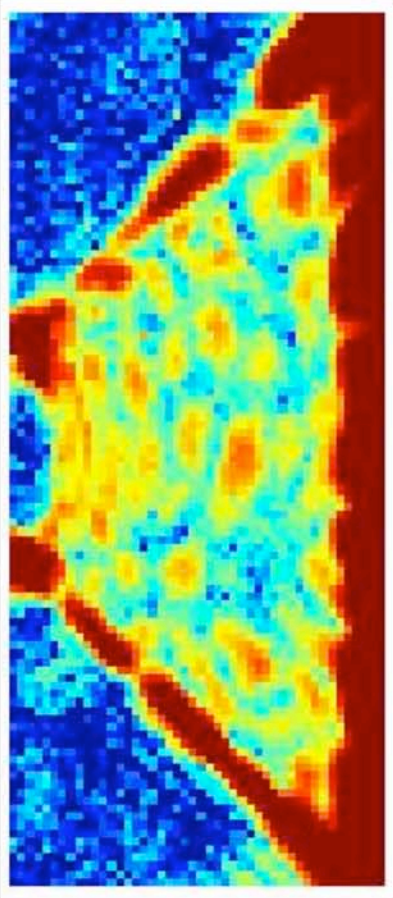
This method is more robust than the previous one we used on the Princeton testbed

$$\begin{bmatrix} I_1^+ - I_1^- \\ \vdots \\ I_k^+ - I_k^- \end{bmatrix} = \frac{1}{4} \begin{bmatrix} \Re \{ C \{ A \psi_1 \} \} & \Im \{ C \{ A \psi_1 \} \} \\ \vdots & \vdots \\ \Re \{ C \{ A \psi_k \} \} & \Im \{ C \{ A \psi_k \} \} \end{bmatrix} \begin{bmatrix} \Re \{ C \{ A e^{\alpha+i\beta} \} \} \\ \Im \{ C \{ A e^{\alpha+i\beta} \} \} \end{bmatrix}$$

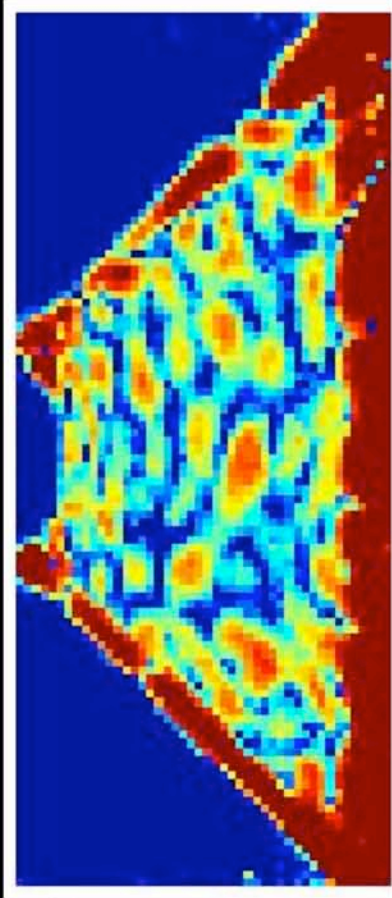


The reconstruction stage

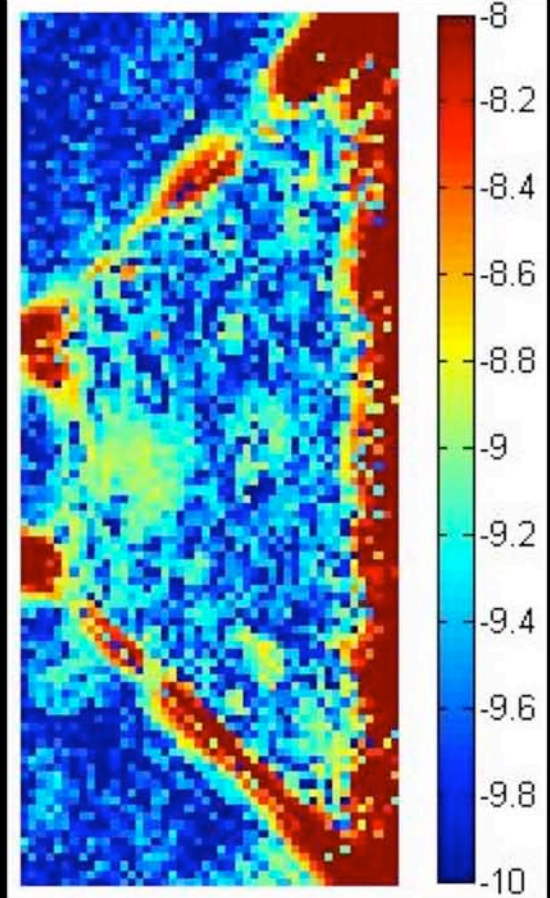
Intensity measurements
(planet added analytically)



Computed intensity from
reconstructed EF



Difference



The added planet simulates a planet, 3 times bigger (in radius) than Earth in the habitable zone of a G-type star 7-8 parsecs away for a 4m telescope imaging at 750nm.



Electric field conjugation

The electric field in the image plane

$$\begin{aligned} E_f &\approx C \{ A e^{\alpha + i\beta} \} + iC \{ A \psi \} \\ &= E_{ab} + iC \{ A \psi \} \end{aligned}$$



Electric field conjugation

The electric field in the image plane

$$\begin{aligned} E_f &\approx C \{ A e^{\alpha + i\beta} \} + iC \{ A\psi \} \\ &= E_{ab} + iC \{ A\psi \} \end{aligned}$$

Assuming linearity of the DM:

$$C \{ A\psi \} = G\bar{a}$$



Electric field conjugation

The electric field in the image plane

$$\begin{aligned} E_f &\approx C \{ A e^{\alpha + i\beta} \} + iC \{ A\psi \} \\ &= E_{ab} + iC \{ A\psi \} \end{aligned}$$

Assuming linearity of the DM:

$$C \{ A\psi \} = G\bar{a}$$

Electric field conjugation:

$$G\bar{a} = iE_{ab}$$



Electric field conjugation

The electric field in the image plane

$$\begin{aligned} E_f &\approx C \{ A e^{\alpha + i\beta} \} + iC \{ A\psi \} \\ &= E_{ab} + iC \{ A\psi \} \end{aligned}$$

Assuming linearity of the DM:

$$C \{ A\psi \} = G\bar{a}$$

Electric field conjugation:

$$G\bar{a} = E$$



Electric field conjugation

The electric field in the image plane

$$\begin{aligned} E_f &\approx C \{ A e^{\alpha+i\beta} \} + iC \{ A\psi \} \\ &= E_{ab} + iC \{ A\psi \} \end{aligned}$$

Assuming linearity of the DM:

$$C \{ A\psi \} = G\bar{a}$$

Electric field conjugation:

$$G\bar{a} = E$$

How do we construct the G matrix?

Each column of G is (analytically) poking an actuator and recording its effect in the image plane. Under the superposition assumption, the effect of the DM in the image plane will be $G\bar{a}$



Electric field conjugation

The electric field in the image plane

$$\begin{aligned} E_f &\approx C \{ A e^{\alpha+i\beta} \} + iC \{ A\psi \} \\ &= E_{ab} + iC \{ A\psi \} \end{aligned}$$

Assuming linearity of the DM:

$$C \{ A\psi \} = G\bar{a}$$

Electric field conjugation:

$$G\bar{a} = E$$

Solution (assuming real valued):

$$\bar{a} = \begin{bmatrix} \Re \{ G \} \\ \dots \\ \Im \{ G \} \end{bmatrix}^{-1} \begin{bmatrix} \Re \{ E \} \\ \dots \\ \Im \{ E \} \end{bmatrix}$$



Electric field conjugation

The electric field in the image plane

$$\begin{aligned} E_f &\approx C \{ A e^{\alpha + i\beta} \} + iC \{ A\psi \} \\ &= E_{ab} + iC \{ A\psi \} \end{aligned}$$

Assuming linearity of the DM:

$$C \{ A\psi \} = G\bar{a}$$

Electric field conjugation:

$$G\bar{a} = E$$

Solution (assuming real valued):

$$\bar{a} = \begin{bmatrix} \Re \{ G \} \\ \dots \\ \Im \{ G \} \end{bmatrix}^{-1} \begin{bmatrix} \Re \{ E \} \\ \dots \\ \Im \{ E \} \end{bmatrix}$$

Interpretation:

$$\bar{a}^* = \arg \min_{\bar{a} \in X} \| G\bar{a} - E \|^2$$



Regularization

Regional weighting in
the image plane:

$$\bar{a} = \begin{bmatrix} \Re \{WG\} \\ \dots \\ \Im \{WG\} \end{bmatrix}^{-1} \begin{bmatrix} \Re \{WE\} \\ \dots \\ \Im \{WE\} \end{bmatrix}$$

$$\bar{a}^* = \arg \min_{\bar{a} \in X} \|WG\bar{a} - WE\|^2$$

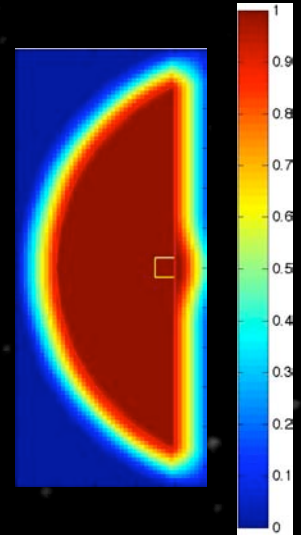


Regularization

Regional weighting in
the image plane:

$$\bar{a} = \begin{bmatrix} \Re \{WG\} \\ \dots \\ \Im \{WG\} \end{bmatrix}^{-1} \begin{bmatrix} \Re \{WE\} \\ \dots \\ \Im \{WE\} \end{bmatrix}$$

$$\bar{a}^* = \arg \min_{\bar{a} \in X} \|WG\bar{a} - WE\|^2$$



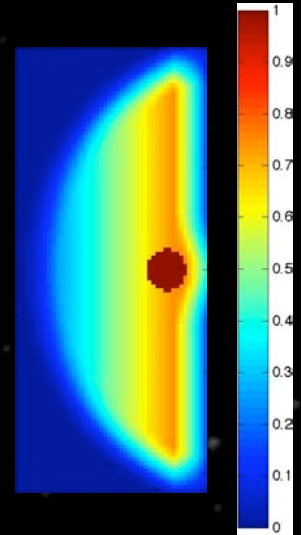


Regularization

Regional weighting in
the image plane:

$$\bar{a} = \begin{bmatrix} \Re \{WG\} \\ \dots \\ \Im \{WG\} \end{bmatrix}^{-1} \begin{bmatrix} \Re \{WE\} \\ \dots \\ \Im \{WE\} \end{bmatrix}$$

$$\bar{a}^* = \arg \min_{\bar{a} \in X} \|WG\bar{a} - WE\|^2$$



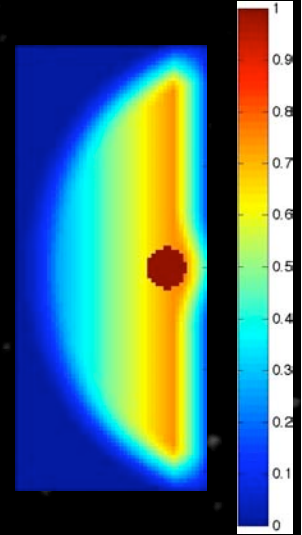


Regularization

Regional weighting in
the image plane:

$$\bar{a} = \begin{bmatrix} \Re\{WG\} \\ \dots \\ \Im\{WG\} \end{bmatrix}^{-1} \begin{bmatrix} \Re\{WE\} \\ \dots \\ \Im\{WE\} \end{bmatrix}$$

$$\bar{a}^* = \arg \min_{\bar{a} \in X} \|WG\bar{a} - WE\|^2$$



Actuators stroke:

$$\bar{a} = \begin{bmatrix} \Re\{G\} \\ \dots \\ \Im\{G\} \\ \dots \\ \mu \begin{bmatrix} 1 & 0 & \dots & 0 \\ 0 & 1 & & \vdots \\ \vdots & & \ddots & 0 \\ 0 & \dots & 0 & 1 \end{bmatrix} \end{bmatrix}^{-1} \begin{bmatrix} \Re\{E\} \\ \dots \\ \Im\{E\} \\ \dots \\ \begin{bmatrix} 0 \\ 0 \\ \vdots \\ 0 \end{bmatrix} \end{bmatrix}$$

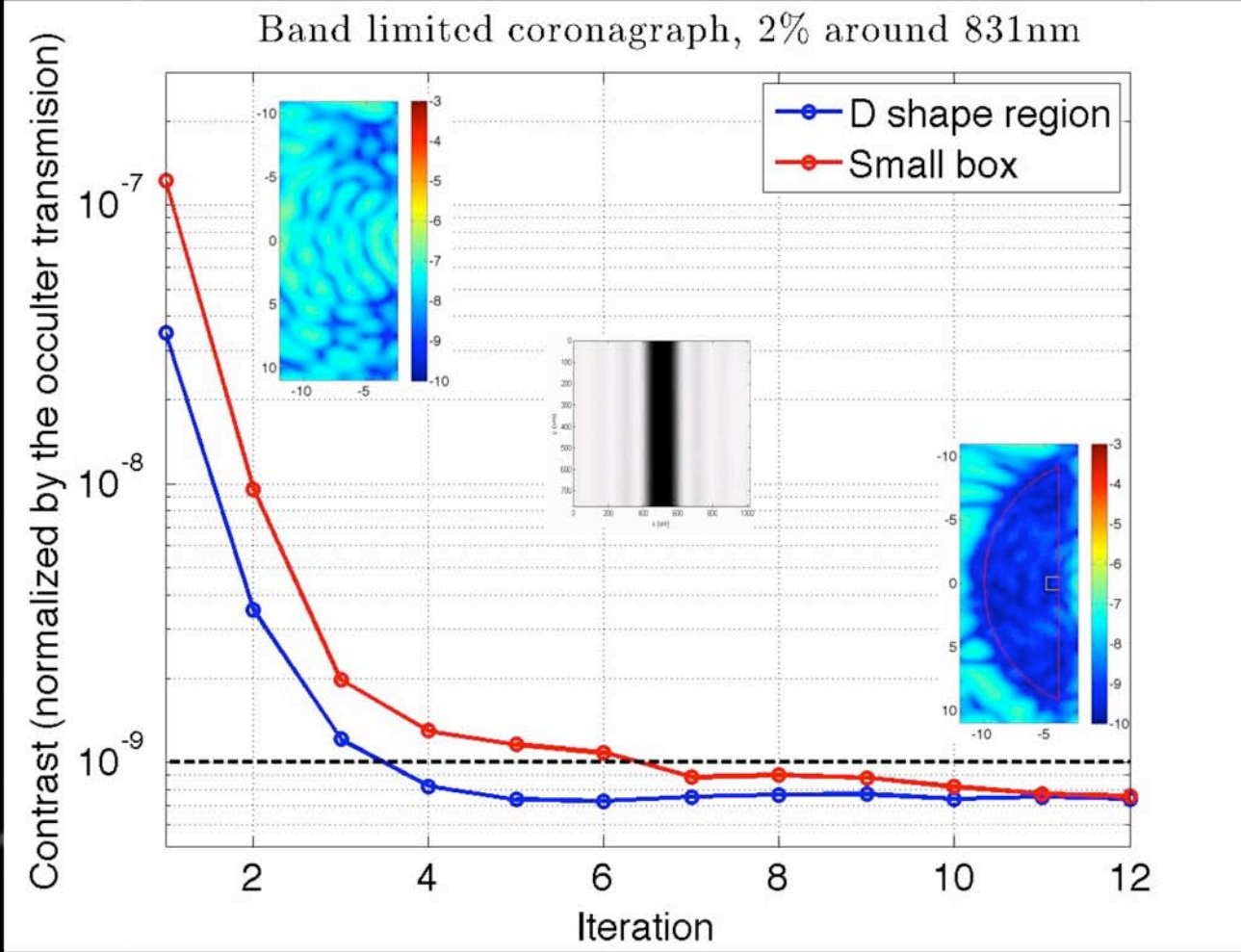
↕ EFC
↕ regularization
↕ Actuators

μ determines the weighting
between contrast and
actuators stroke

$$\bar{a}^* = \arg \min_{\bar{a} \in X} \|G\bar{a} - E\|^2 + \mu^2 \|\bar{a}\|^2$$



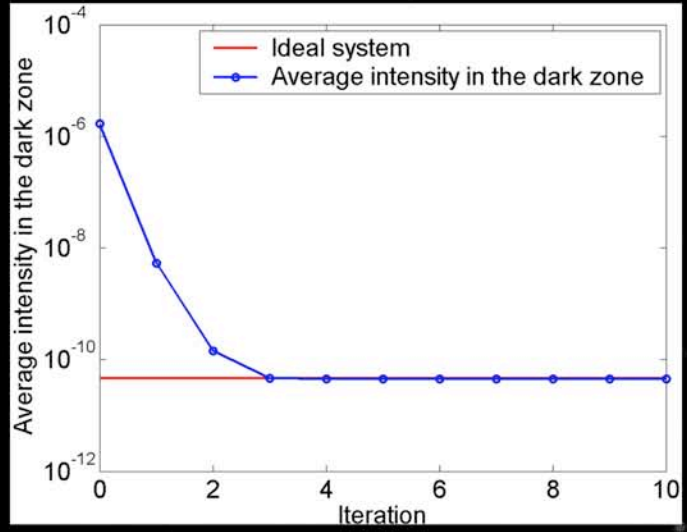
Experimental results



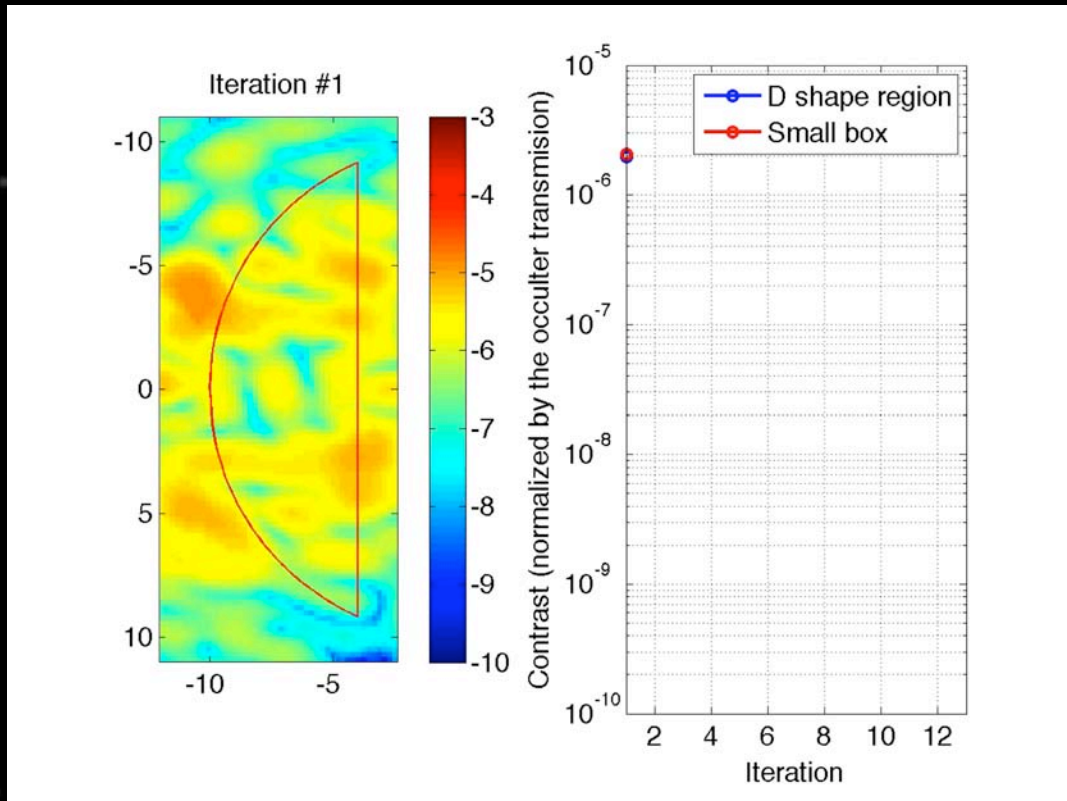


Experimental results

Simulations shown last year



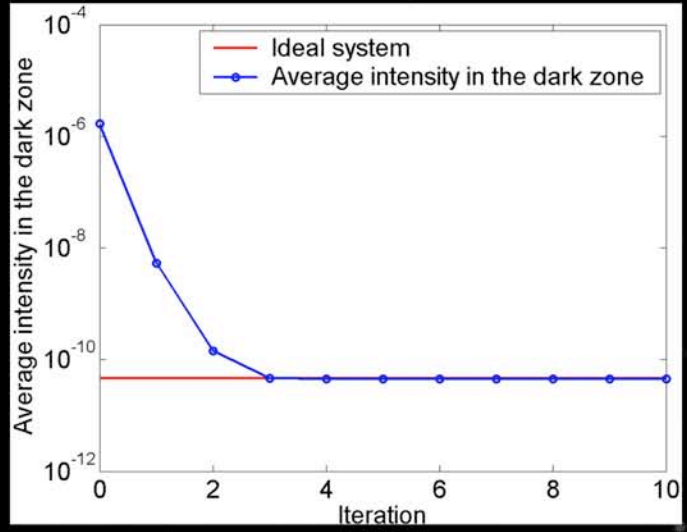
Experimental results



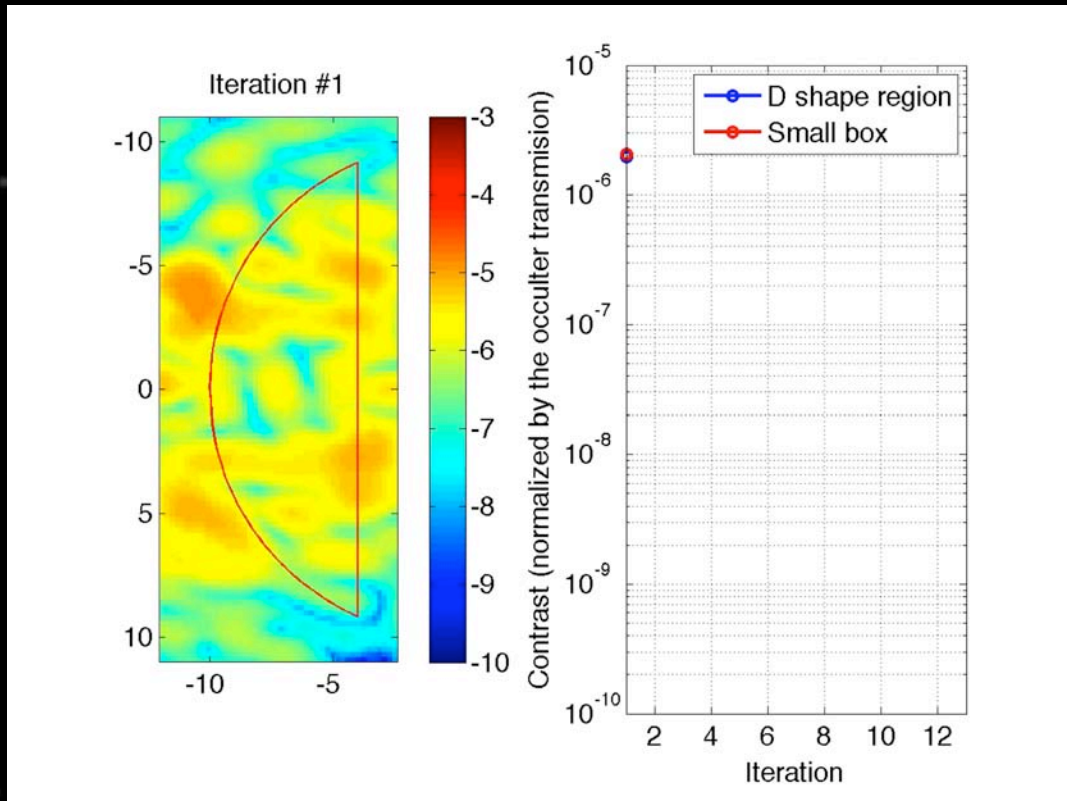


Experimental results

Simulations shown last year

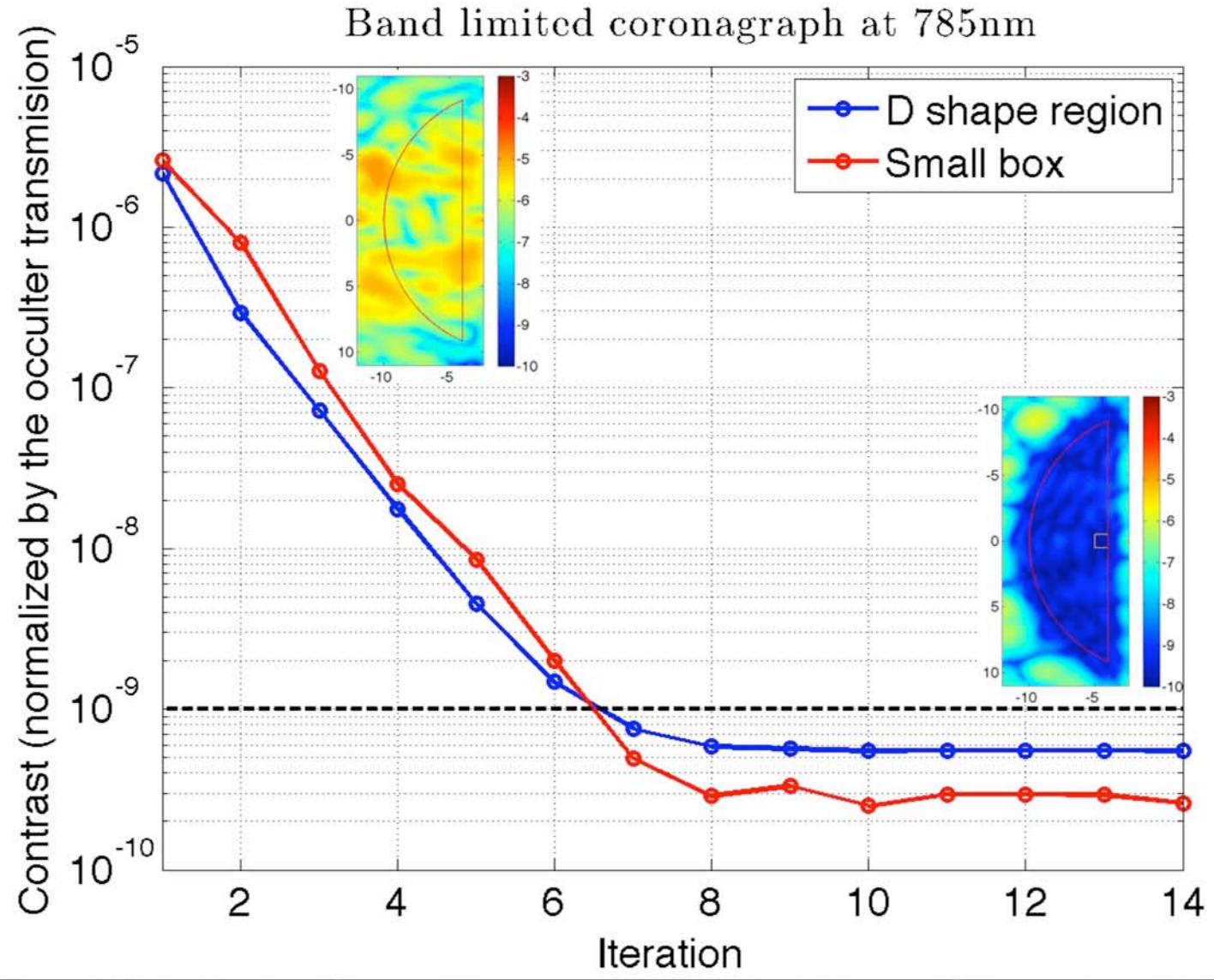


Experimental results



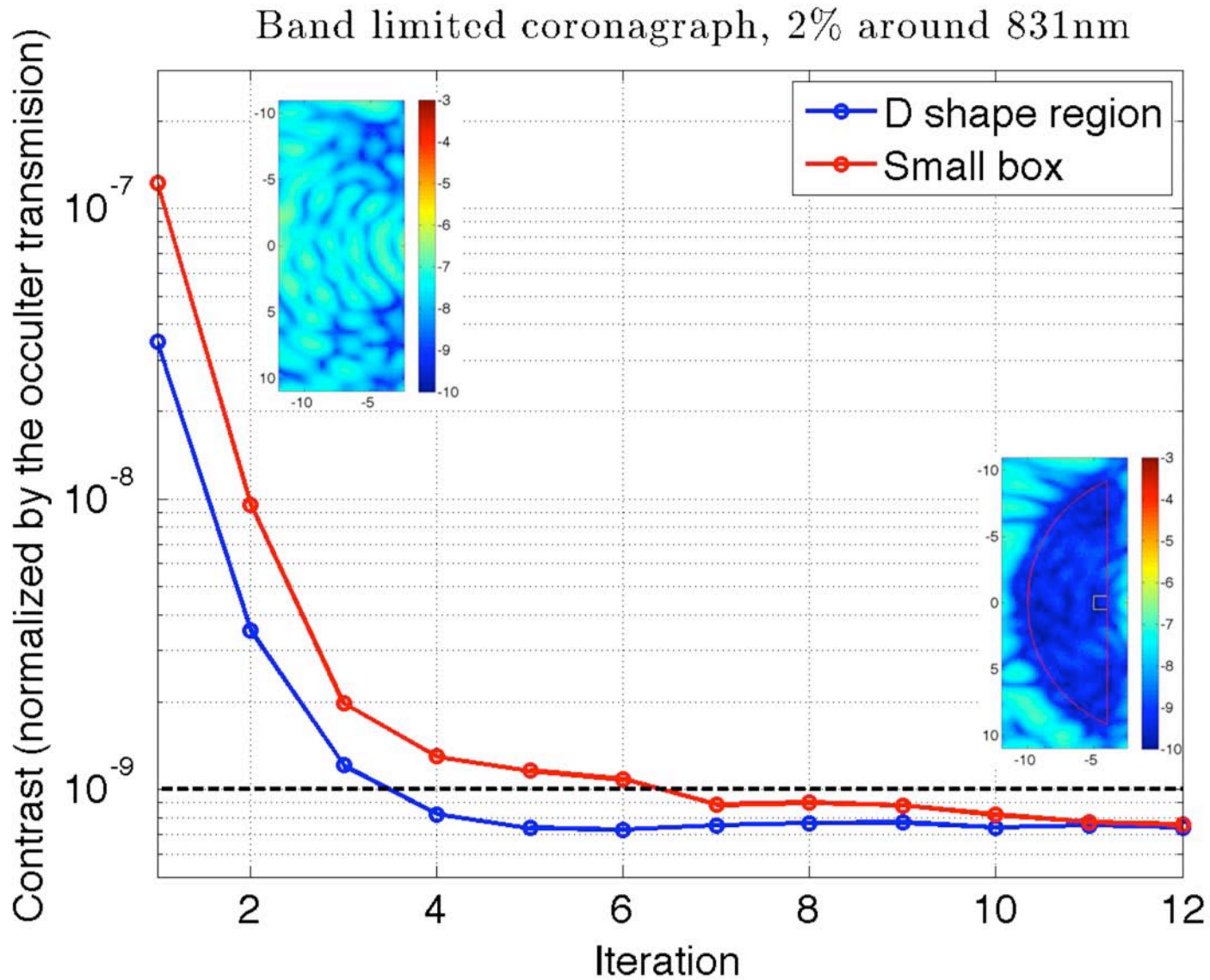


Experimental results



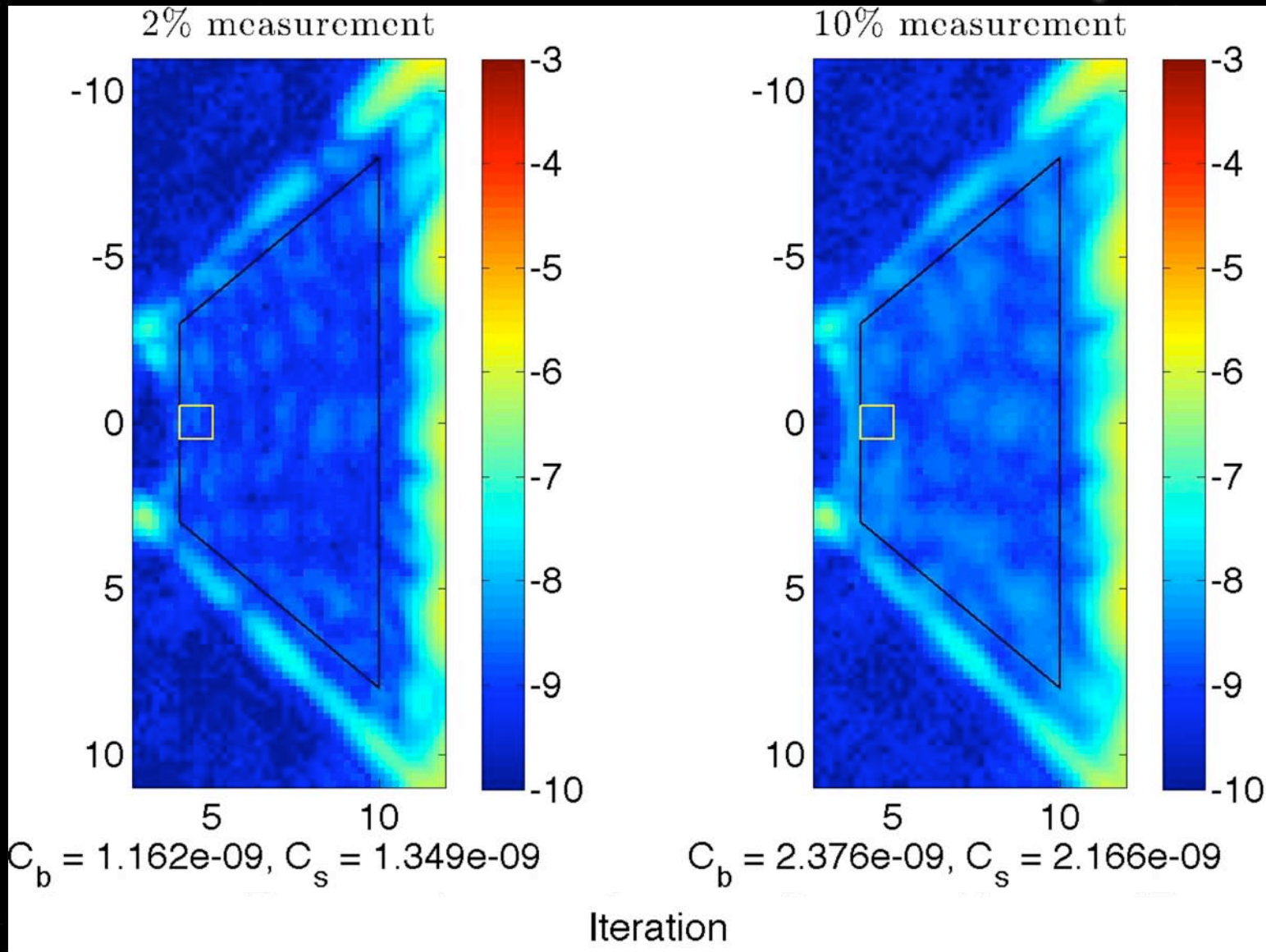


Experimental results





Experimental results





Broadband correction

Reconstruct the electric field at different wavelengths... and then,

$$\bar{a} = \begin{bmatrix} \Re\{W_{\lambda_1} G_{\lambda_1}\} \\ \Im\{W_{\lambda_1} G_{\lambda_1}\} \\ \vdots \\ \Re\{W_{\lambda_k} G_{\lambda_k}\} \\ \Im\{W_{\lambda_k} G_{\lambda_k}\} \\ \dots \\ \mu \begin{bmatrix} 1 & 0 & \dots & 0 \\ 0 & 1 & & \vdots \\ \vdots & & \ddots & 0 \\ 0 & \dots & 0 & 1 \end{bmatrix} \end{bmatrix}^{-1} \begin{bmatrix} \Re\{W_{\lambda_1} E_{\lambda_1}\} \\ \Im\{W_{\lambda_1} E_{\lambda_1}\} \\ \vdots \\ \Re\{W_{\lambda_k} E_{\lambda_k}\} \\ \Im\{W_{\lambda_k} E_{\lambda_k}\} \\ \dots \\ \begin{bmatrix} 0 \\ 0 \\ \vdots \\ 0 \end{bmatrix} \end{bmatrix}$$

\updownarrow
 Electric field
 conjugation

 \updownarrow
 Actuators
 regularization

$$\bar{a}^* = \arg \min_{\bar{a} \in X} \|G_{\lambda_1} \bar{a} - E_{\lambda_1}\|^2 + \|G_{\lambda_2} \bar{a} - E_{\lambda_2}\|^2 + \dots + \|G_{\lambda_k} \bar{a} - E_{\lambda_k}\|^2 + \mu^2 \|\bar{a}\|^2$$



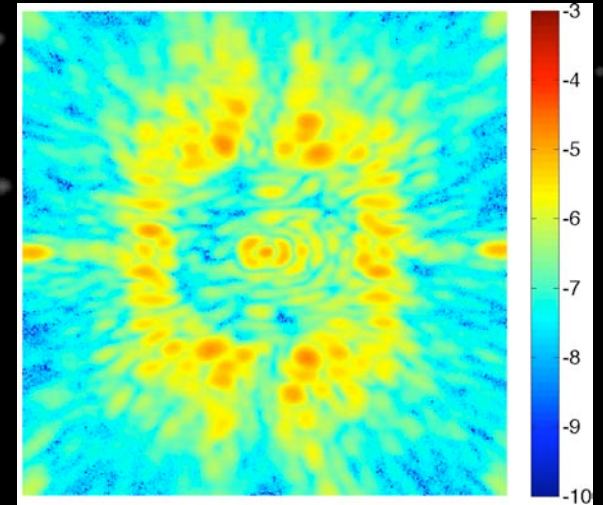
Broadband correction

Reconstruct the electric field at different wavelengths... and then,

$$\bar{a} = \begin{bmatrix} \Re\{W_{\lambda_1} G_{\lambda_1}\} \\ \Im\{W_{\lambda_1} G_{\lambda_1}\} \\ \vdots \\ \Re\{W_{\lambda_k} G_{\lambda_k}\} \\ \Im\{W_{\lambda_k} G_{\lambda_k}\} \\ \dots \\ \mu \begin{bmatrix} 1 & 0 & \dots & 0 \\ 0 & 1 & & \vdots \\ \vdots & & \ddots & 0 \\ 0 & \dots & 0 & 1 \end{bmatrix} \end{bmatrix}^{-1} \begin{bmatrix} \Re\{W_{\lambda_1} E_{\lambda_1}\} \\ \Im\{W_{\lambda_1} E_{\lambda_1}\} \\ \vdots \\ \Re\{W_{\lambda_k} E_{\lambda_k}\} \\ \Im\{W_{\lambda_k} E_{\lambda_k}\} \\ \dots \\ \begin{bmatrix} 0 \\ 0 \\ \vdots \\ 0 \end{bmatrix} \end{bmatrix}$$

\Uparrow
 Electric field
 conjugation
 \Downarrow

 \Uparrow
 Actuators
 regularization
 \Downarrow



$$\bar{a}^* = \arg \min_{\bar{a} \in X} \|G_{\lambda_1} \bar{a} - E_{\lambda_1}\|^2 + \|G_{\lambda_2} \bar{a} - E_{\lambda_2}\|^2 + \dots + \|G_{\lambda_k} \bar{a} - E_{\lambda_k}\|^2 + \mu^2 \|\bar{a}\|^2$$



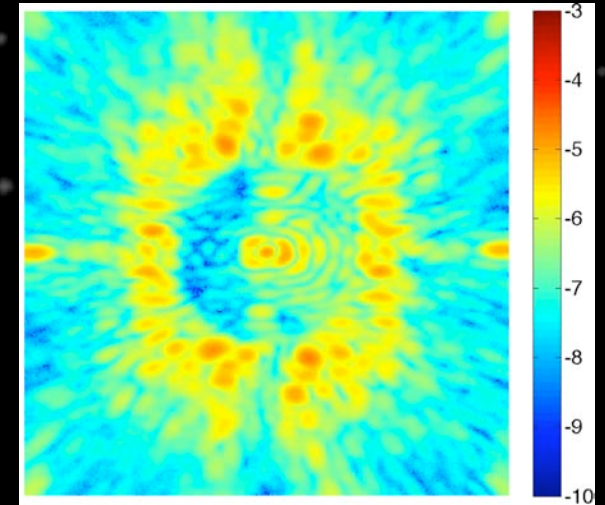
Broadband correction

Reconstruct the electric field at different wavelengths... and then,

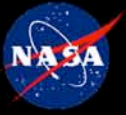
$$\bar{a} = \begin{bmatrix} \Re\{W_{\lambda_1} G_{\lambda_1}\} \\ \Im\{W_{\lambda_1} G_{\lambda_1}\} \\ \vdots \\ \Re\{W_{\lambda_k} G_{\lambda_k}\} \\ \Im\{W_{\lambda_k} G_{\lambda_k}\} \\ \dots \\ \mu \begin{bmatrix} 1 & 0 & \dots & 0 \\ 0 & 1 & & \vdots \\ \vdots & & \ddots & 0 \\ 0 & \dots & 0 & 1 \end{bmatrix} \end{bmatrix}^{-1} \begin{bmatrix} \Re\{W_{\lambda_1} E_{\lambda_1}\} \\ \Im\{W_{\lambda_1} E_{\lambda_1}\} \\ \vdots \\ \Re\{W_{\lambda_k} E_{\lambda_k}\} \\ \Im\{W_{\lambda_k} E_{\lambda_k}\} \\ \dots \\ \begin{bmatrix} 0 \\ 0 \\ \vdots \\ 0 \end{bmatrix} \end{bmatrix}$$

\Uparrow
 Electric field
 conjugation
 \Downarrow

 \Uparrow
 Actuators
 regularization
 \Downarrow



$$\bar{a}^* = \arg \min_{\bar{a} \in X} \|G_{\lambda_1} \bar{a} - E_{\lambda_1}\|^2 + \|G_{\lambda_2} \bar{a} - E_{\lambda_2}\|^2 + \dots + \|G_{\lambda_k} \bar{a} - E_{\lambda_k}\|^2 + \mu^2 \|\bar{a}\|^2$$



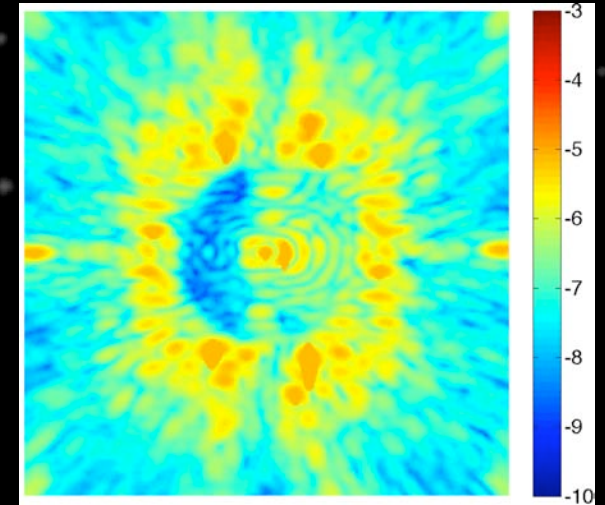
Broadband correction

Reconstruct the electric field at different wavelengths... and then,

$$\bar{a} = \begin{bmatrix} \Re\{W_{\lambda_1} G_{\lambda_1}\} \\ \Im\{W_{\lambda_1} G_{\lambda_1}\} \\ \vdots \\ \Re\{W_{\lambda_k} G_{\lambda_k}\} \\ \Im\{W_{\lambda_k} G_{\lambda_k}\} \\ \dots \\ \mu \begin{bmatrix} 1 & 0 & \dots & 0 \\ 0 & 1 & & \vdots \\ \vdots & & \ddots & 0 \\ 0 & \dots & 0 & 1 \end{bmatrix} \end{bmatrix}^{-1} \begin{bmatrix} \Re\{W_{\lambda_1} E_{\lambda_1}\} \\ \Im\{W_{\lambda_1} E_{\lambda_1}\} \\ \vdots \\ \Re\{W_{\lambda_k} E_{\lambda_k}\} \\ \Im\{W_{\lambda_k} E_{\lambda_k}\} \\ \dots \\ \begin{bmatrix} 0 \\ 0 \\ \vdots \\ 0 \end{bmatrix} \end{bmatrix}$$

\updownarrow
 Electric field
 conjugation

 \updownarrow
 Actuators
 regularization

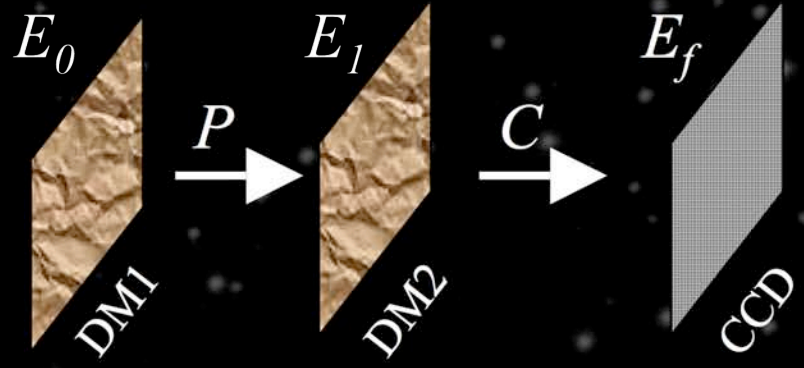


$$\bar{a}^* = \arg \min_{\bar{a} \in X} \|G_{\lambda_1} \bar{a} - E_{\lambda_1}\|^2 + \|G_{\lambda_2} \bar{a} - E_{\lambda_2}\|^2 + \dots + \|G_{\lambda_k} \bar{a} - E_{\lambda_k}\|^2 + \mu^2 \|\bar{a}\|^2$$



Broadband correction

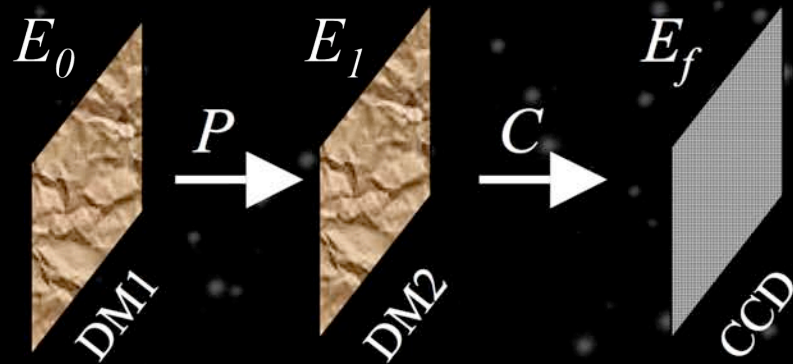
What about using more than one DM?





Broadband correction

What about using more than one DM?

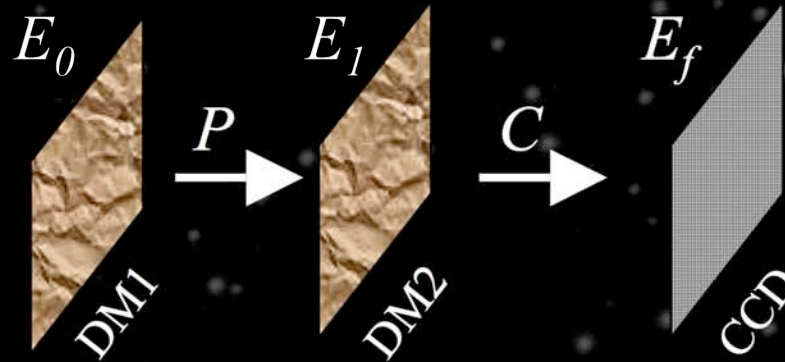


The formulation shown in the previous slide can be used for a multi-DM system. **Its all about the G matrix!**



Broadband correction

What about using more than one DM?



The formulation shown in the previous slide can be used for a multi-DM system. **Its all about the G matrix!**

Just like before, each column of the G matrix will be the effect in the image plane of a single DM actuator. Actuators from DM1 will have the additional effect from propagating between E_0 and E_1 .



Summary

- 2.37×10^{-9} contrast for SPC at 10% wavelength band around 800nm.
- 7×10^{-10} contrast for BLC at 2% wavelength band around 832nm.
- 7×10^{-10} contrast for BLC at monochromatic light around 785nm.